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U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

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**APPLICANTS: Sun Jennifer; Wu Shun; Thach Senh; Kumar Ananda; Wu Robert; Wang Hong; Lin Yixing; Stow Clifford; 156					
**CONTINUING DATA VERIFIED:					
** FOREIGN APPLICATIONS VERIFIED:					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>			
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no		35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO 005120 USA/ETCH/IBSS	
Verified and Acknowledged Examiners's initials					
TITLE : Yttrium oxide based surface coating for semiconductor IC processing vacuum chambers U.S. DEPT. OF COMM. /PAT. & TM-PTO-436L (Rev. 12-94)					

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NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drwg.	Figs. Drwg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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